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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: KAWAGUCHI et al  
Serial No.: 10/688,991  
Filed: October 21, 2003  
For: Plasma Processing Method And Apparatus  
Art Unit: 3742  
Examiner: T. Hoang

**AMENDMENT**

Mail Stop: Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 18, 2005

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the office action dated October 18, 2004. The amendments are listed below and set forth on the following pages.

Amendments to the Specification;

Amendments to the Claims; and

Remarks are included following the amendments.